

INFORMATION DISCLOSURE CITATION PTO-1449	Atty. Docket No. 010817	Serial No. 09/891,611
	Applicant: Mamoru NAKASUJI et al.	
	Filing Date: June 27, 2001	Group Art Unit:

FOREIGN PATENT DOCUMENTS

		Document No.	Date	Country	Translation (Yes or No)
	JB 18 2001 AC	52-115161 ✓	09/27/77	JAPAN	ABSTRACT
	JB AC	52-117567 ✓✓	10/03/77	JAPAN	ABSTRACT
	JB AC	57-072326 ✓	05/06/82	JAPAN	ABSTRACT
	JB AD	57-125871 ✓✓	08/05/82	JAPAN	ABSTRACT
	JB AE	60-000741 ✓	01/05/85	JAPAN	ABSTRACT
	JB AF	62-195838 ✓	08/28/87	JAPAN	ABSTRACT
	JB AG	03-022339 ✓	01/30/91	JAPAN	ABSTRACT
	JB AH	03-053439 ✓✓	03/07/91	JAPAN	ABSTRACT
	JB AI	03-102814 ✓	04/30/91	JAPAN	ABSTRACT
	JB AJ	03-266350 ✓	11/27/91	JAPAN	ABSTRACT
	JB AK	03-276548 ✓✓	12/06/91	JAPAN	ABSTRACT
	JB AL	04-266350 ✓	09/22/92	JAPAN	ABSTRACT
	JB AM	05-063261 ✓	03/12/93	JAPAN	ABSTRACT
	JB AN	05-251316 ✓✓	09/28/93	JAPAN	ABSTRACT
	JB AO	07-065766 ✓	03/10/95	JAPAN	ABSTRACT
	JB AP	08-138611 ↗	05/31/96	JAPAN	ABSTRACT
	JB AQ	09-311112 ↗	12/02/97	JAPAN	ABSTRACT
	JB AR	10-062503 ↗	03/06/98	JAPAN	ABSTRACT
	JB AS	10-177952 ↘	06/30/98	JAPAN	ABSTRACT
	JB AT	11-132975 ✓	05/21/99	JAPAN	ABSTRACT
	JB AU	2000-090868 ✓	03/31/00	JAPAN	ABSTRACT

Examiner	/Jack Berman/	Date Considered	06/22/2006
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Examiner Initial		Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
OJB	JAN 18 2002 SEARCHED & TRADE DRAWINGS OFFICE	AV 6,125,522	Nakasuji	10/03/00			11/12/96
JB	AY 5,994,704	SW 6,087,667	Nakasuji et al.	07/11/00			09/30/97
JB	AZ 5,981,947	AX 5,892,224	Nakasuji	11/30/99			10/03/97
JB	BA 5,770,863	BB 5,763,893	Nakasuji et al.	11/09/99			02/03/98
JB	BC 5,751,538	BD 5,747,819	Nakasuji	04/06/99			05/09/97
JB	BE 5,362,968	BF 5,359,197	Miyoshi et al.	06/23/98			10/24/96
JB	BG 4,912,052		Komatsu et al.	06/09/98			12/16/96
JB			Miyoshi et al.	05/12/98			09/26/96
JB				05/05/98			10/30/96
JB				11/08/94			09/27/93
JB				10/25/94			07/16/93
JB				03/27/90			09/23/88

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JB	BH	Low Voltage and high speed operating electrostatic wafer chuck using sputtered tantalum oxide membrane, Mamoru Nakasuji et al., J. Vac. Sci. Technol. A 12(5), Sep/Oct 1994, American Vacuum Society pp. 2834-2839.
JB	BI	High -Emissance and Low-Brightness Electron Gun for Reducing-Image Projection System: Computer Simulation, Mamoru Nakasuji et al., Jpn. J. Appl. Phys. Vol. 36 (1997) pp.2404-2408.
JB	BJ	H. Hayashi, et al., LSI Testing Symposium 1998, Minutes of the meeting, P160 (1998) (partial translation)

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<div style="border: 1px solid black; border-radius: 50%; width: 100px; height: 100px; margin-bottom: 10px;"></div> <p style="margin: 0;">JB</p> <p style="margin: 0;">JAN 18 2002</p> <p style="margin: 0;">JB</p> <p style="margin: 0;">SEARCHED & TRADEMAKED</p> <p style="margin: 0;">JB</p> <p style="margin: 0;">-----</p> <table border="0" style="width: 100%; border-collapse: collapse;"> <tr> <td style="width: 15%;">BK ✓</td> <td><i>Multi-Beam Concepts for Nanometer Devices</i>, B. Lischke et al., Japanese Journal of Applied Physics, Vol. 28, No.10, October 1989, pp. 2058-2064.</td> </tr> <tr> <td style="width: 15%;">BL ✓</td> <td><i>An electron-beam inspecting system for x-ray mask production</i>, P. Sandland et al., J. Vac. Sci. Technol. B9 (6), Nov/Dec. 1991, American Vacuum Society, pp.3005-3009.</td> </tr> <tr> <td style="width: 15%;">BM ✓</td> <td><i>Requirements and performance of an electron-beam column designed for x-ray mask inspection</i>, W.D. Meisburger et al., J. Vac. Sci. Technol. B9 (6), Nov/Dec 1991, American Vacuum Society, pp.3010-3014.</td> </tr> <tr> <td style="width: 15%;">BN ✓</td> <td><i>Table 5-1 Work Function in Metals</i> page 116.</td> </tr> </table>			BK ✓	<i>Multi-Beam Concepts for Nanometer Devices</i> , B. Lischke et al., Japanese Journal of Applied Physics, Vol. 28, No.10, October 1989, pp. 2058-2064.	BL ✓	<i>An electron-beam inspecting system for x-ray mask production</i> , P. Sandland et al., J. Vac. Sci. Technol. B9 (6), Nov/Dec. 1991, American Vacuum Society, pp.3005-3009.	BM ✓	<i>Requirements and performance of an electron-beam column designed for x-ray mask inspection</i> , W.D. Meisburger et al., J. Vac. Sci. Technol. B9 (6), Nov/Dec 1991, American Vacuum Society, pp.3010-3014.	BN ✓	<i>Table 5-1 Work Function in Metals</i> page 116.
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	Filing Date: June 27, 2001	Group Art Unit: TBA

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JB	AA 4,944,645	Suzuki	7/31/90			
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	AC					

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JB	AE	09-073872 ✓	3/18/97	Japan	Yes/Abstract
JB	AF	2000-100369 ✓	4/7/00	Japan	Yes/Abstract
JB	AG	2000-003692 ✓	1/7/00	Japan	Yes/Abstract
JB	AH	2000-133565 ✓	5/12/00	Japan	Yes/Abstract
JB	AI	62-100936 ✓	5/11/87	Japan	Yes/Abstract
JB	AJ	10-125271 ✓	5/15/98	Japan	Yes/Abstract
JB	AK	11-233062 ✓	8/27/99	Japan	Yes/Abstract
JB	AL	2000-149843 ✓	5/30/00	Japan	Yes/Abstract
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